

# LIGA R&D and Prototyping

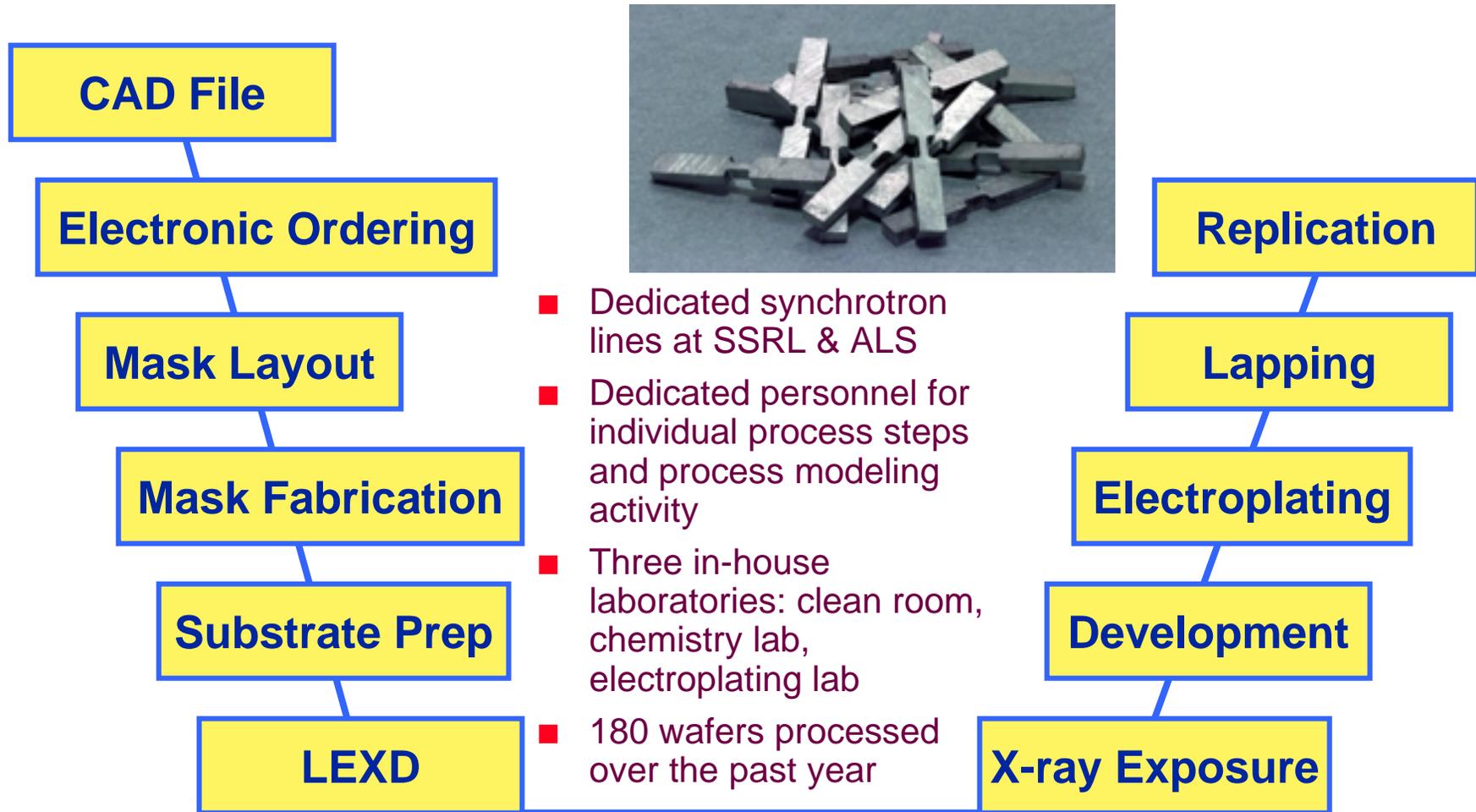
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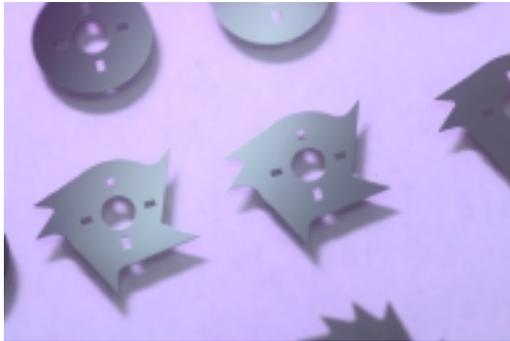
SEMICONWEST 1999  
San Francisco, California  
July 14, 1999



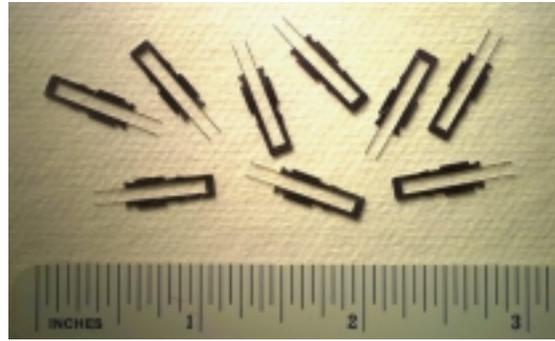
# Sandia has a complete capability for prototyping microparts



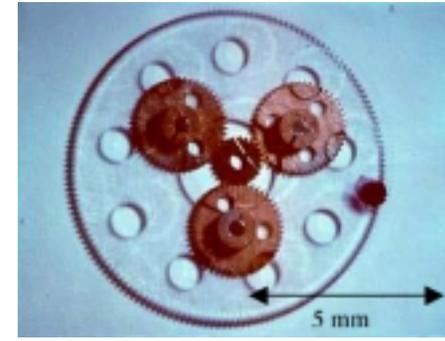
# Sandia's processing capability has supported a variety of applications



Individual parts



Assembly Tools



Microsystems

- Defense: low g accelerators, motors, locking mechanisms, precision piece parts
- Instrumentation miniaturization: klystrons, mass spectrometers and wave-guides (with JPL), gas chromatography columns, Faraday cups ....
- Precision Devices: heat pipes, plunge EDM tools, fiber alignment and clamps, micropart assembly tools ....

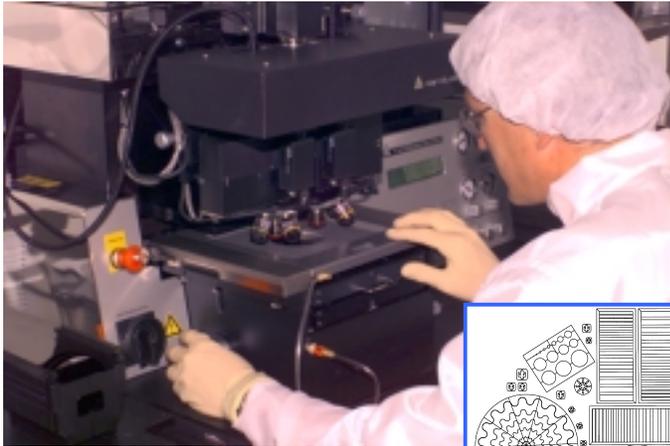
# LIGA Processing Capability: Electronic Ordering and Data Tracking



- CAD files and orders can be transferred electronically to an ftp site
- Allows a requester to follow a part through the fabrication process
- Allows members of the fab team to follow parts and processes
- Serves as an inventory record
- Automatically archives process conditions - important for high consequence reliability applications
- Provides the opportunity to search based on process conditions

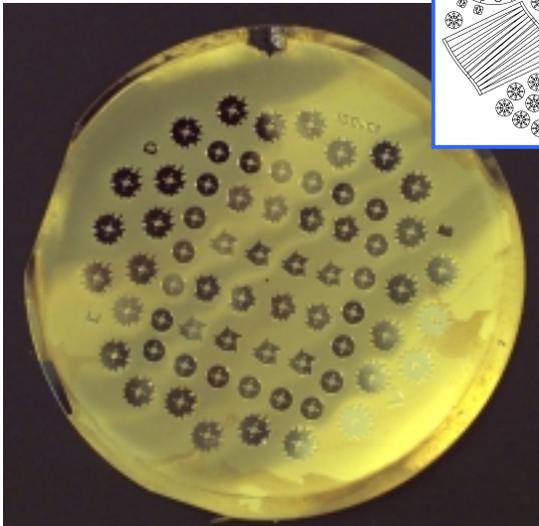
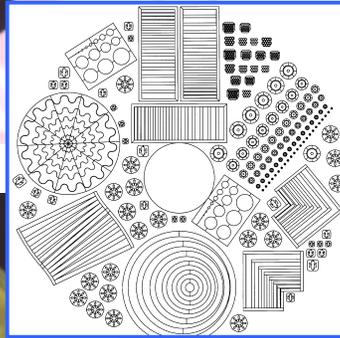
★ <http://daytona.ca.sandia.gov/LIGA>

# LIGA Processing Capability: Masks & Substrate



## ★ LIGA Mask

- Multi-user clean room facilities with class 100 room equipped for lithography
- Silicon wafer 100 microns thick
- 3 or 4 inch diameter format
- Patterned gold up to 30 microns thick using SJR 5740 photoresist, Karl Suss MA6 aligner



## ★ LIGA Substrate

- CQ grade PMMA used as thick resist
- Bonded to Ti-Cu-Ti metallized 600 micron silicon wafer plating base
- Fly-cut to +50 microns over desired final part thickness

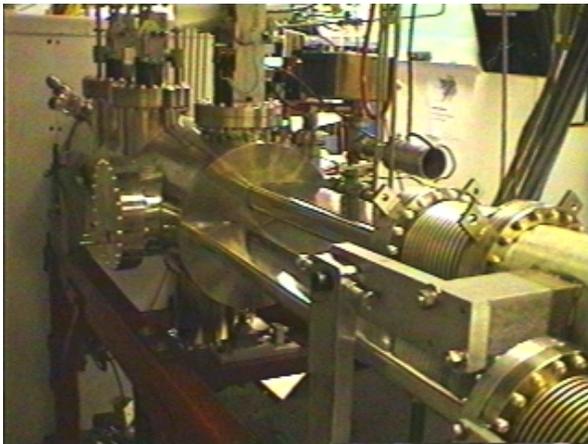
# LIGA Processing Capability: Beam Lines

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## ★ SSRL - Stanford Synchrotron Radiation Laboratory

- SSRL BL2-2 has been used by the West Coast LIGA Group (Sandia, JPL, LBL) since 1995 using an independent experimenter proposal
- SSRL BL3-1 is a dedicated LIGA station to be operated by Sandia and JPL and scheduled for commissioning in July 1999

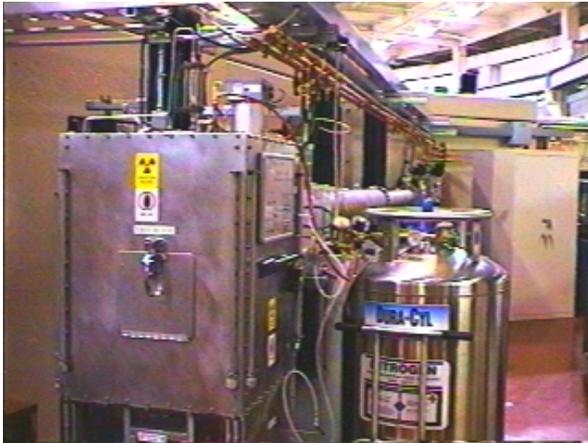


# LIGA Processing Capability: Beam Lines

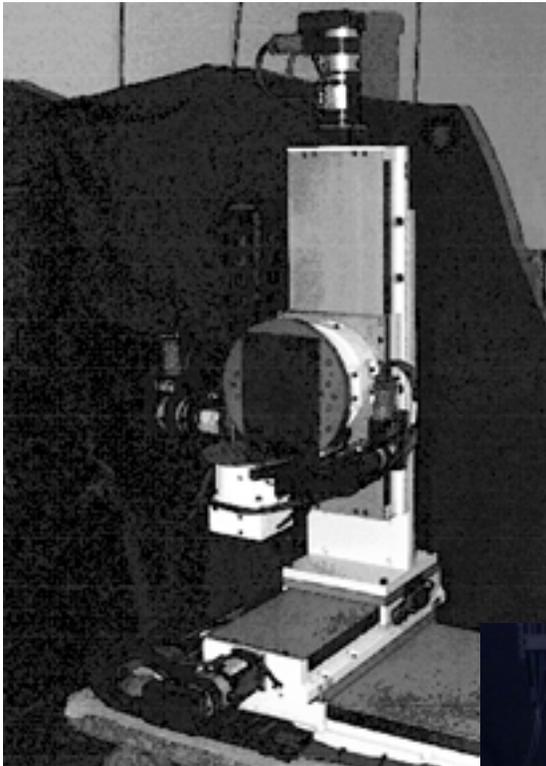


## ★ ALS - Advanced Light Source

- ALS BL3.3.2 is shared by the West Coast LIGA Group (Sandia, JPL, LBL) and consists of a self-contained end station dedicated to LIGA
- The X-ray exposure scanner consists of a turret design capable of mounting multiple masks simultaneously

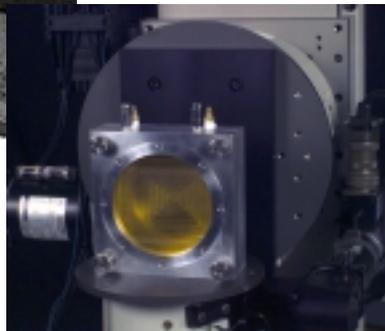


# LIGA Processing Capability: X-ray Scanner

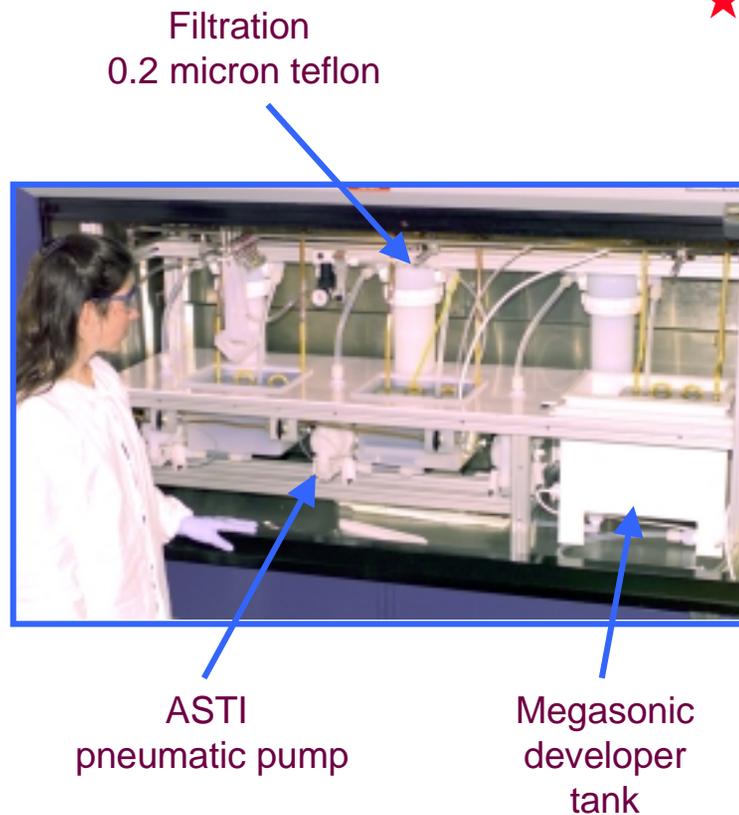


## ★ SSRL BL3-1 will incorporate a 5 stage instrument for exposing samples using Deep Etch X-ray lithography:

- Vertical Z-axis scanning stage with 18 inches of travel
- Horizontal X-axis with 12 inches of travel
- Horizontal Y-axis with 24 inches of travel
- Two rotational stages to which the mask holder is attached
- Labview control and data acquisition
- Laser and camera sample alignment



# LIGA Processing Capability: Development



## ★ Megasonic development system:

- Three tanks:
  - GG developer
  - intermediate rinse
  - water rinse
- 0.2 micron teflon filtration
- This system can handle multiple 3" and 4" substrates; megasonics is incorporated into the developer and intermediate rinse tanks
- A camera and video system mounted to the hood is used to monitor the development progress



# LIGA Processing Capability: Electroplating & Planarization



## ★ Electroplating

- 16 tank plating line for copper, nickel, permalloy, gold, research
- 5 micron bath filtration
- computer-based diagnostic and control - specialty waveform generation

## ★ Planarization

- Engis lapping equipment & diamond slurries
- modified vacuum fixture to hold wafers
- thickness tolerance is +/- 5 microns with surface finish of 1 micron rms

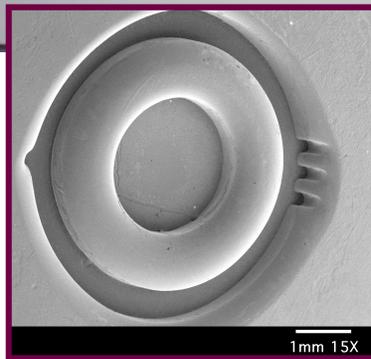
# LIGA Processing Capability: LEXD computer code

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- ★ Provides integrated calculation of both exposure and development and supports all synchrotron sources in use by Sandia
- ★ Filter set and mask design is greatly simplified and can input:
  - filter and mask elements directly -- code computes dose
  - top or bottom dose -- code computes exposure time
  - top and bottom dose -- code selects filters and time
  - masked dose or side wall erosion depth -- code selects mask thickness and filters and time
- ★ Development rates and total time are computed for both masked and exposed regions:
  - calculations include dissolution kinetics and fragment transport
  - results provide estimate of development time as well as side wall erosion and potential for undercutting of substrate



# LIGA Processing Capability: Replication



Standard Lucite  
PMMA sheet

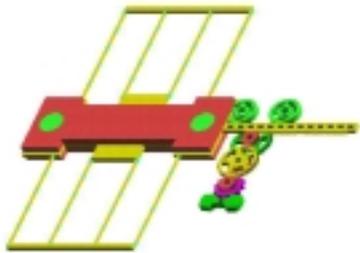
## ★ Polymeric replication

- Hot embossing:
  - replication quality vs material using modified Instron machine
  - mold technology
  - high flow / low flow parameters
- Injection Molding:
  - Acquisition of vertical molding machine

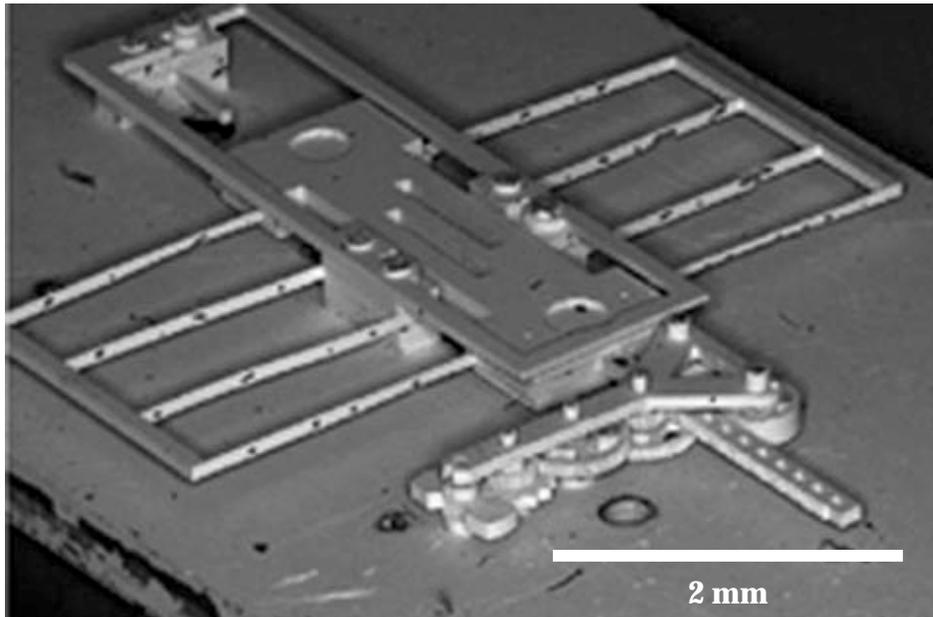
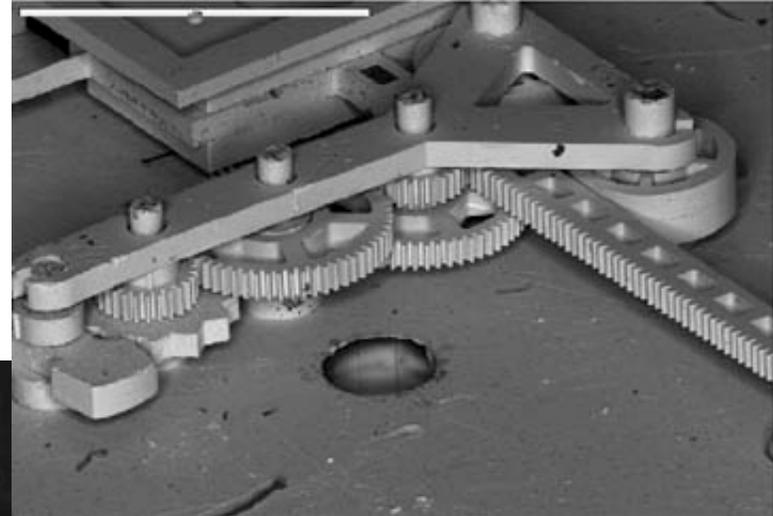
## ★ Ceramic replication

- nanoparticles + polymeric binder + LIGA mold

# LIGA Accomplishments



Microtrajectory safety subsystem component to provide enhanced safety for weapon systems



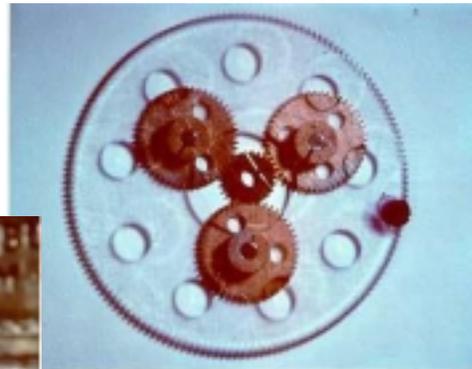
## Environmental Sensing Device

- 10mm x 6mm x 3mm package
- 45 piece parts
- 25 - 500 micron thickness
- copper, nickel, nickel/iron

# LIGA Accomplishments

## Millimotor:

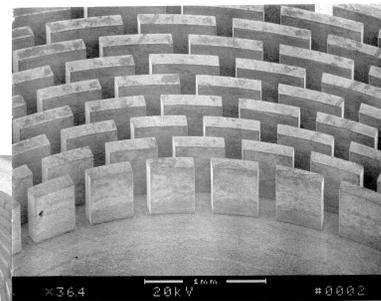
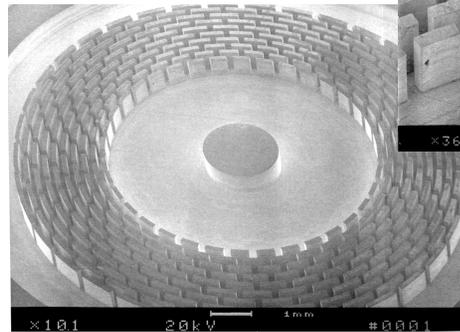
- Variable reluctance
- 8 mm dia x 3 mm deep



- 30 LIGA parts
- 4 materials (PMMA, copper, nickel, permalloy)
- 3 week delivery

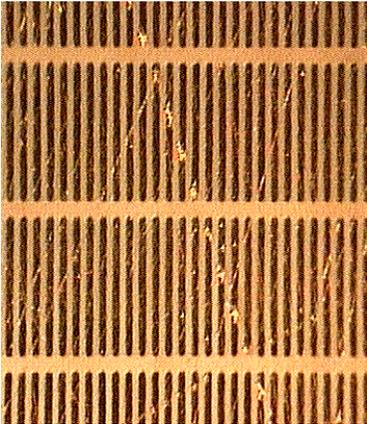
## EDM Tool:

- kovar and stainless steel parts
- 1 mm thick, 15 mm dia

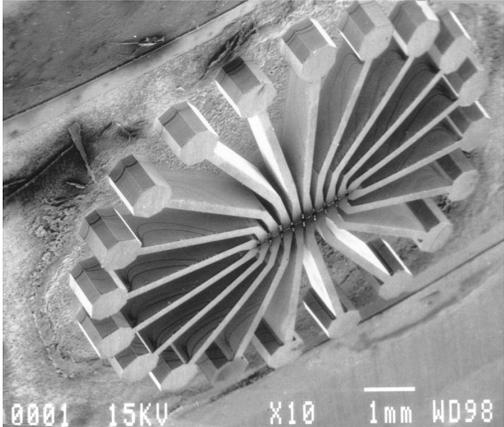


- 6 patterns on each wafer
- copper patterns on copper substrate
- Current R&D for polymeric replication to reduce cost

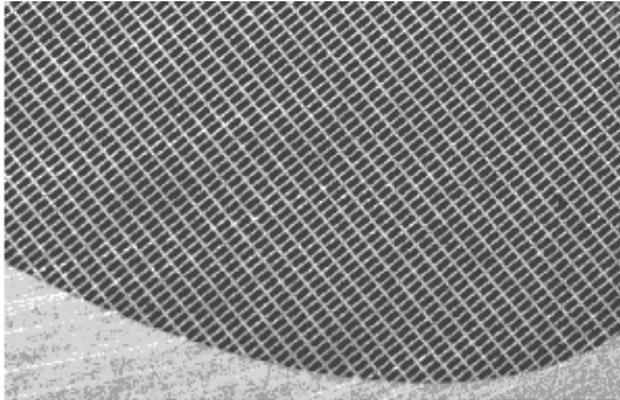
# LIGA Accomplishments



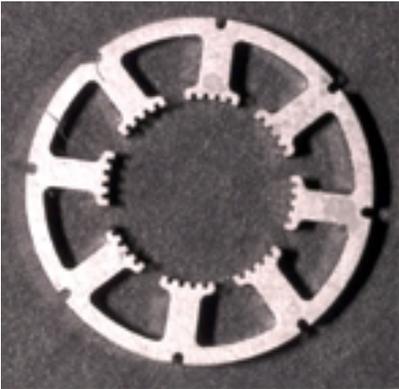
X-ray imaging grid  
(JPL/SNL)  
34 micron pitch



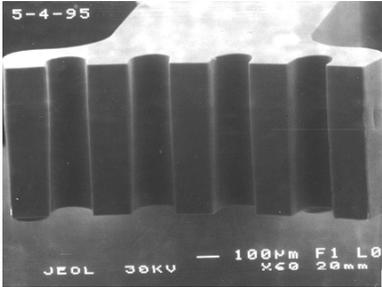
Mass spectrometer  
component 1 mm thick



640 GHz wave-guide  
(JPL design /SNL  
plated)  
40 micron wide slats;  
320 x 144 micron  
openings



Precision stepper motor  
(LBNL/SNL)  
Step Size 1.8 Degree, Ni/Fe Alloy  
Requires vertical side wall and high precision

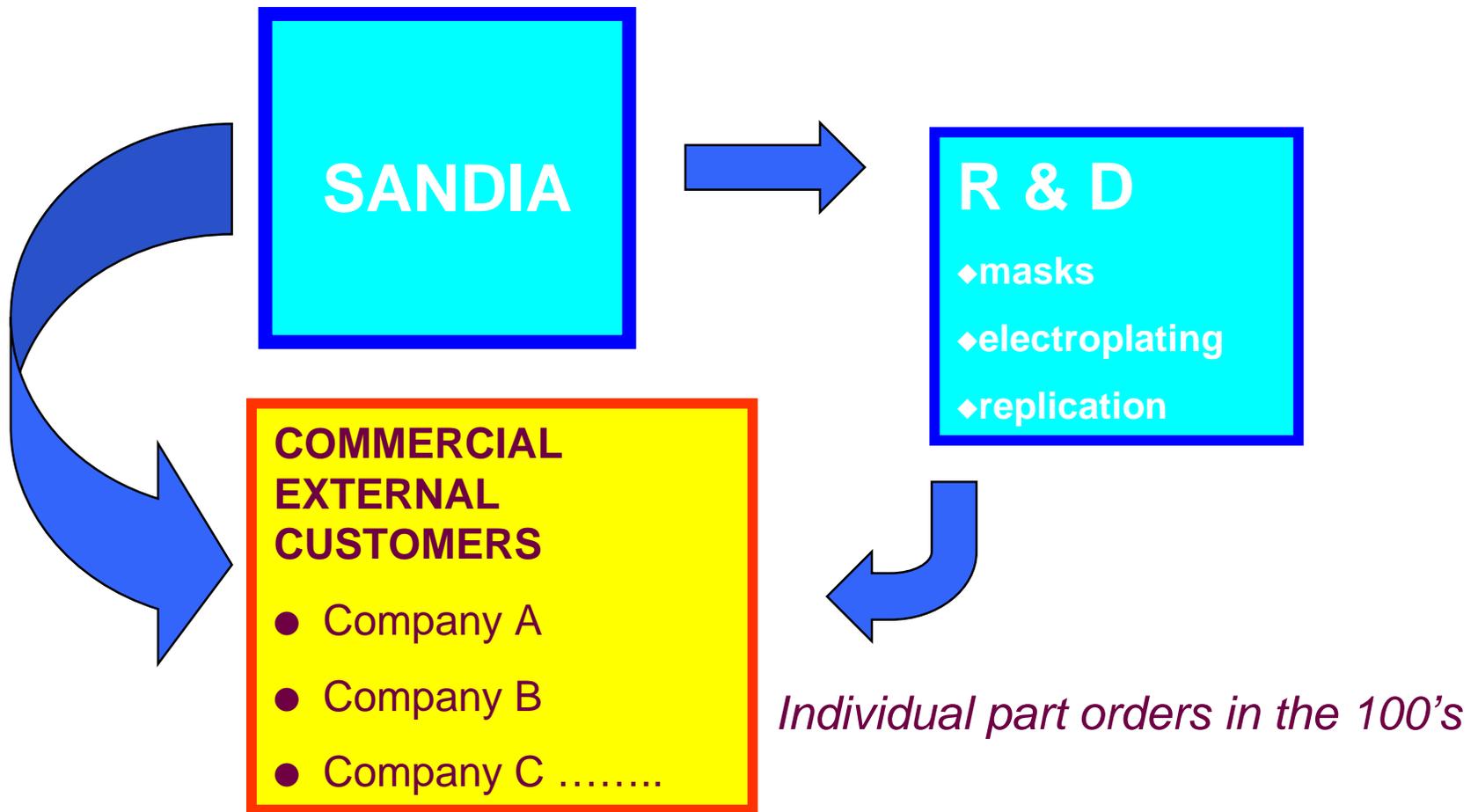


Micro Electro-  
chromatography  
capillary connectors  
(SNL)



# What's Today?

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# What's Tomorrow?

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# What's Tomorrow and The Next Day?



★ **If external LIGA business increases !**

- more machines ?
- more people ?
  - more continuous \$ ?

★ **Sandia would provide the interface and R&D when needed**

- 1 FOUNDRY
- more than 1 FOUNDRY?

**EXTERNAL LIGA**

*Individual part orders  
in the 1000's - 10,000'S*